

**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

Claims 1-10 (Canceled)

11. (Previously presented) A process meter, comprising:  
a sensor which can be mounted in a wall of a vessel for holding or conveying a process medium,  
an electronics case for meter electronics which is mechanically, particularly rigidly, coupled to said sensor, and  
at least one vibration absorber, wherein:  
said electronics case is at least intermittently subjected to vibrations generated in or transmitted via said sensor; and  
in order to reduce amplitudes of possible vibrations of said electronics case, said at least one vibration absorber which is vibrated at least intermittently in order to dissipate vibrational energy taken into said electronics case is affixed to a wall of said electronics case.

12. (Previously presented) The process meter as set forth in claim 11, wherein:  
said at least one vibration absorber is positioned at a distance, particularly as far as possible, from a joint between said sensor and said electronics case.

13. (Previously presented) The process meter as set forth in claim 11, wherein:  
said at least one vibrated vibration absorber has a quality factor,  $Q_D$ , which is lower than a quality factor,  $Q_G$ , of said vibrating electronics case.

14. (Previously presented) The process meter as set forth in claim 11, wherein:

said at least one vibrated vibration absorber has a quality factor,  $Q_D$ , in the range of 1 to 5, particularly on the order of 3.

15. (Previously presented) The process meter as set forth in claim 11, wherein:

said at least one vibration absorber has a resonant frequency,  $f_D$ , which differs from a resonant frequency,  $f_G$ , of said electronics case by about 10% at the most.

16. (Previously presented) The process meter as set forth in claim 11, wherein:

said at least one vibration absorber has a resonant frequency,  $f_D$ , which is less than a resonant frequency,  $f_G$ , of said electronics case.

17. (Previously presented) The process meter as set forth in claim 11, wherein:

said at least one vibration absorber has a mass,  $m_D$ , which is greater than 1% of a mass,  $m_G$ , of said electronics case.

18. (Previously presented) The process meter as set forth in claim 11, wherein:

said at least one vibration absorber is disposed within said electronics case.

19. (Previously presented) The process meter as set forth in claim 11, wherein:

said at least one vibration absorber comprises a disk- or cup-shaped plastic body having a, particularly disk- or plate-shaped, metal body fitted or embedded therein.

20. (Previously presented) The process meter as set forth in claim 11, wherein:

said at least one vibration absorber comprises a plastic body which is affixed to the wall of said electronics case, particularly with adhesive.

21. (Previously presented) The process meter as set forth in claim 11, wherein:

the process meter is selected from a group consisting of: level limit monitors; pressure gauges; electromagnetic flowmeters; vortex flowmeters; Coriolis mass flowmeters; densimeters, viscometers, ultrasonic flowmeters, and ultrasonic level meters.

22. (New) The process meter as set forth in claim 11, wherein:  
said electronics case is screwed onto a necklike portion of the sensor.

23. (New) The process meter as set forth in claim 11, wherein:  
said sensor is mounted in a wall of a pipe.

24. (New) The process meter as set forth in claim 11, wherein:  
said sensor is mounted in a wall of a tank.

25. (New) A process meter, comprising:  
a sensor for sensing at least one process variable, said sensor being mounted in a wall of a vessel,

an electronics case for meter electronics, said electronics case being mechanically coupled to said sensor, and said electronics case being at least intermittently subjected to vibrations; and

at least one vibration absorber for reducing amplitudes of vibrations of the electronics case, said at least one vibration absorber being located within said electronics case.

26. (New) The process meter as claimed in claim 25, wherein:  
said at least one vibrated vibration absorber has a quality factor,  $QD$ , which is lower than a quality factor,  $QG$ , of said vibrating electronics case.

27. (New) The process meter as claimed in claim 25, wherein:  
said at least one vibrated vibration absorber has a quality factor,  $QD$ , in the range of 1 to 5.

28. (New) The process meter as set forth in the foregoing claim, wherein:  
said at least one vibrated vibration absorber has quality factor,  $QD$ , on the order of 3.

29. (New) The process meter as claimed in claim 25, wherein:  
said at least one vibration absorber has a resonant frequency,  $fD$ , which differs from a resonant frequency,  $fG$ , of said electronics case by about 10% at the most.

30. (New) The process meter as claimed in claim 25, wherein:  
said at least one vibration absorber has a resonant frequency,  $fD$ , which is less than a resonant frequency,  $fG$ , of said electronics case.

31. (New) The process meter as claimed in claim 25, wherein:  
said at least one vibration absorber has a mass,  $mD$ , which is greater than 1% of a mass,  $mG$ , of said electronics case.

32. (New) The process meter as claimed in claim 25, wherein:  
said at least one vibration absorber comprises a disk- or cup-shaped plastic body having a metal body fitted or embedded therein.

33. (New) The process meter as set forth in the foregoing claim, wherein:  
said metal body is disk- or plate-shaped.

34. (New) The process meter as claimed in claim 25, wherein:  
said at least one vibration absorber is affixed to a wall of said electronics case.

35. (New) The process meter as claimed in claim 25, wherein:  
said at least one vibration absorber is positioned at a distance from a joint  
between said sensor and said electronics case.

36. (New) The process meter as set forth in the foregoing claim, wherein:  
said at least one vibration absorber is positioned as far as possible from the joint  
between said sensor and said electronics case.

37. (New) The process meter as set forth in the foregoing claim, wherein:  
said at least one vibration absorber comprises a plastic body which is affixed to  
the wall of said electronics case.

38. (New) The process meter as set forth in the foregoing claim, wherein:  
said at least one vibration absorber is affixed to the wall of said electronics case  
with adhesive.

39. (New) The process meter as claimed in claim 25, wherein:  
said electronics case is screwed onto a necklike portion of the sensor.

40. (New) The process meter as claimed in claim 25, wherein;  
said electronics case is rigidly coupled to said sensor.

41. (New) The process meter as claimed in claim 25, wherein;  
the vibrations, to which the electronics case is subjected at least intermittently,  
are generated in the sensor.

42. (New) The process meter as claimed in claim 25, wherein:  
the vibrations, to which the electronics case is subjected at least intermittently,  
are transmitted via the sensor.

43. (New) The process meter as claimed in claim 25, wherein:  
the vessel, in which the sensor is mounted, is a pipe.

44. (New) The process meter as claimed in claim 25, wherein;  
the vessel, in which the sensor is mounted, is a tank.

45. (New) The process meter as claimed in claim 25, wherein:  
said process meter is selected from a group consisting of level limit monitors,  
pressure gages, electromagnetic flowmeters, vortex flowmeters, Coriolis mass  
flowmeters, densimeters, viscometers, ultrasonic flowmeters, and ultrasonic level  
meters.